



PATENT APPLICATION *IFW \$*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q77490

Fumiyuki NISHIYAMA, et al.

Appln. No.: 10/669,603

Group Art Unit: 1713

Confirmation No.: 1317

Examiner: Satya B. Sastri

Filed: September 25, 2003

For: POSITIVE RESIST COMPOSITION AND PATTERN FORMATION METHOD USING
THE SAME

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of one month(s), extending the time for responding to the Office Action of June 13, 2005 to October 13, 2005.

A check for the statutory fee of \$120.00 is attached. The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this sheet is enclosed.

10/14/2005 SZEWDIE1 00000073 10669603

01 FC:1251

120.00 OP

SUGHRUE MION, PLLC
Telephone: (202) 293-7060
Facsimile: (202) 293-7860

WASHINGTON OFFICE

23373

CUSTOMER NUMBER

Respectfully submitted,

Lisa E. Stahl
Registration No. 56,704

Date: October 13, 2005